



Corres. and Mail  
**BOX AF**

AF FFW

RESPONSE UNDER 37 CFR 1.116  
EXPEDITED PROCEDURE  
EXAMINING GROUP 2851

00862.022246

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Kazunori IWAMOTO et al.

Application No.: 09/866,600

Filed: May 30, 2001

For: STAGE APPARATUS WHICH SUPPORTS INTERFEROMETER,  
STAGE POSITION MEASUREMENT METHOD, PROJECTION  
EXPOSURE APPARATUS, PROJECTION EXPOSURE  
APPARATUS MAINTENANCE METHOD SEMICONDUCTOR  
DEVICE MANUFACTURING METHOD, AND  
SEMICONDUCTOR MANUFACTURING FACTORY

)  
: Examiner: H. Nguyen  
)  
: Group Art Unit: 2851  
)  
: Confirmation No.: 4961  
)  
:

August 6, 2004

**Mail Stop AF**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Transmitted herewith is an Amendment in the above-identified application.

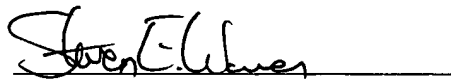
☒ No additional fee is required.

The fee has been calculated as shown below:

CLAIMS AS AMENDED						
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL CLAIMS	30	MINUS	31	= 0	x \$9 \$18	\$0.00
INDEP. CLAIMS	6	MINUS	7	= 0	x \$43 \$86	\$0.00
Fee for Multiple Dependent claims \$145/\$290						—
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT						\$0.00

- ☐ °Verified Statement claiming small entity status is enclosed, if not filed previously.
- ☐ A check in the amount of \$\_\_\_ is enclosed including the additional claims fees.
- ☐ Charge \$\_\_\_ to Deposit Account No. 06-1205. A duplicate of this sheet is enclosed.
- ☒ Any prior general authorization to charge an issue fee under 37 CFR 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 CFR 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate of this paper is enclosed.
- ☐ A check in the amount of \$\_\_\_ to cover the fee for a two month extension is enclosed.
- ☐ A check in the amount of \$\_\_\_ to cover the Information Disclosure Statement fee is enclosed.
- ☒ Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address given below.

Respectfully submitted,

  
\_\_\_\_\_  
Attorney for Applicants  
Steven E. Warner  
Registration No. 33,326

FITZPATRICK, CELLA, HARPER & SCINTO  
30 Rockefeller Plaza  
New York, New York 10112-3801  
Facsimile: (212) 218-2200



RESPONSE UNDER 37 CFR 1.116  
EXPEDITED PROCEDURE  
EXAMINING GROUP 2851

00862.022246

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	)	
	:	Examiner: H. Nguyen
Kazunori IWAMOTO et al.	)	
	:	Group Art Unit: 2851
Application No.: 09/866,600	)	
	:	Confirmation No.: 4961
Filed: May 30, 2001	)	
	:	
For: STAGE APPARATUS WHICH SUPPORTS	)	August 6, 2004
INTERFEROMETER, STAGE POSITION	:	
MEASUREMENT METHOD, PROJECTION	)	
EXPOSURE APPARATUS, PROJECTION	:	
EXPOSURE APPARATUS MAINTENANCE	)	
METHOD, SEMICONDUCTOR DEVICE	:	
MANUFACTURING METHOD, AND	)	
SEMICONDUCTOR MANUFACTURING FACTORY :	:	

**Mail Stop AF**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL REJECTION

Sir:

In response to the final Official Action dated May 7, 2004, please amend the above-identified application as follows, pursuant to 37 C.F.R. § 1.116: